

The Atomistic-Continuum Modeling of Short Pulse Laser melting of Semiconductors

V.P. Lipp^{*} ^{1,2}, D.S. Ivanov^{1,2}, B. Rethfeld¹, M.E. Garcia²

²*University of Kassel, ¹Technical University of Kaiserslautern
Kassel, Kaiserslautern
Germany*

*12 December 2012
Palaiseau, France*



**v.p.lipp@gmail.com*

Outline

1. Experiments of laser irradiation of silicon

2. Continuum approach to modeling silicon

3. MD-TTM coupled approach

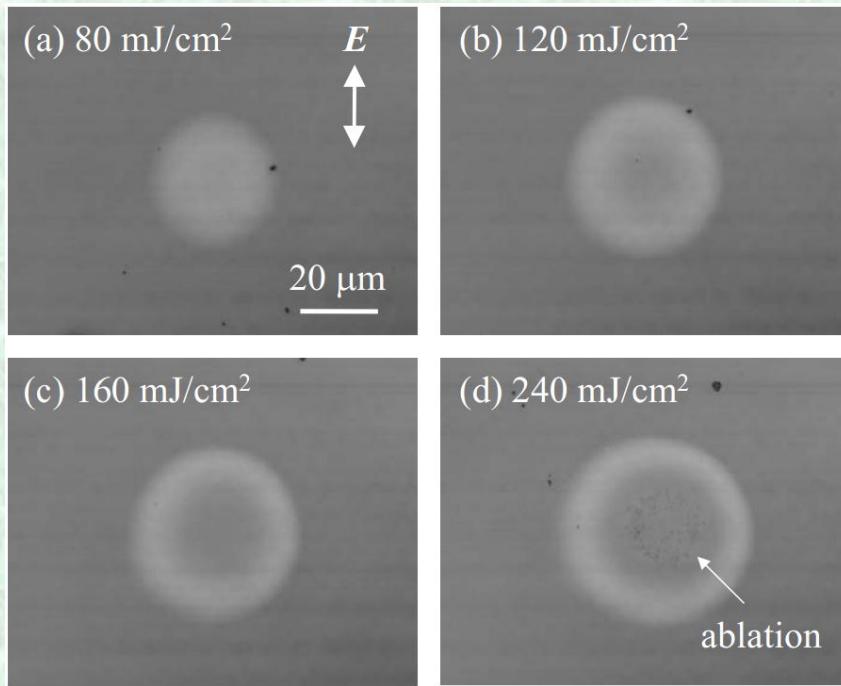
4. First results:

- Continuum model vs. MD-TTM**
- Comparison to experiment**

5. Conclusion

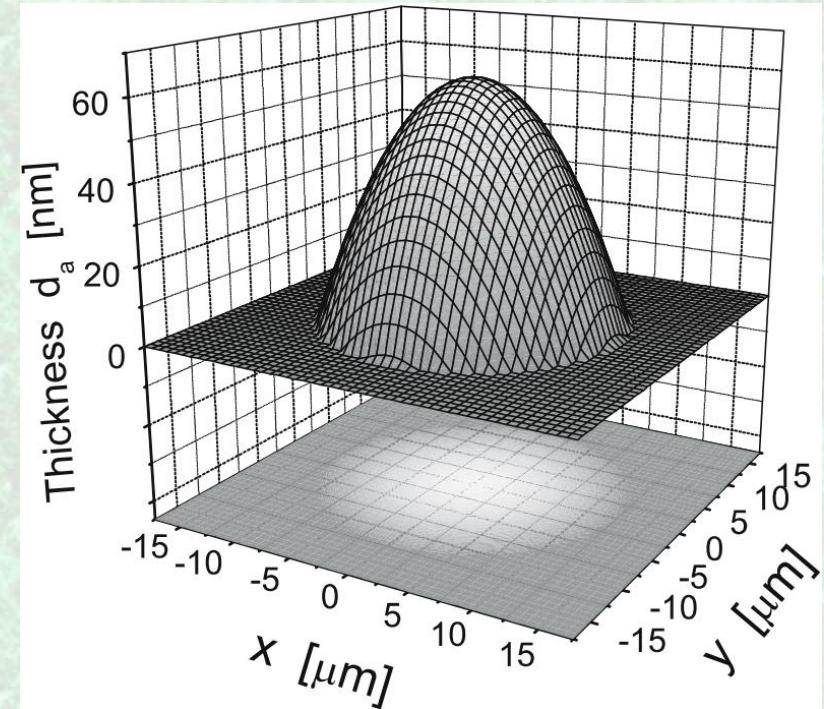
6. Future work

Motivation: nanostructuring on silicon



Processed Si surface by a single shot of 267 nm femtosecond laser irradiation.
(LSM images)

Y. Izawa et al., J. Appl. Phys. 105, 064909 (2009)



3D-profile of the amorphous layer thickness induced by 130fs, 800nm laser pulse with fluence 4200 J/m²

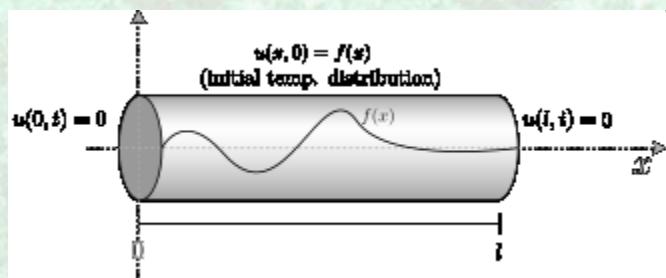
J. Bonse, Appl. Phys. A: Mater. Sci. Proc., A 84, 63-66 (2006)

Model requirements

- Absorption: generation of e--h+ pairs due to 1-photon and 2-photon absorption; absorption by free carriers
- Strong nonequilibrium state between laser-excited free carriers and lattice
- Fast heat conduction process due to free carriers
- Fast free carrier diffusion process
- Fast nonequilibrium phase transitions

Part I

Continuum modeling of silicon (TTM)

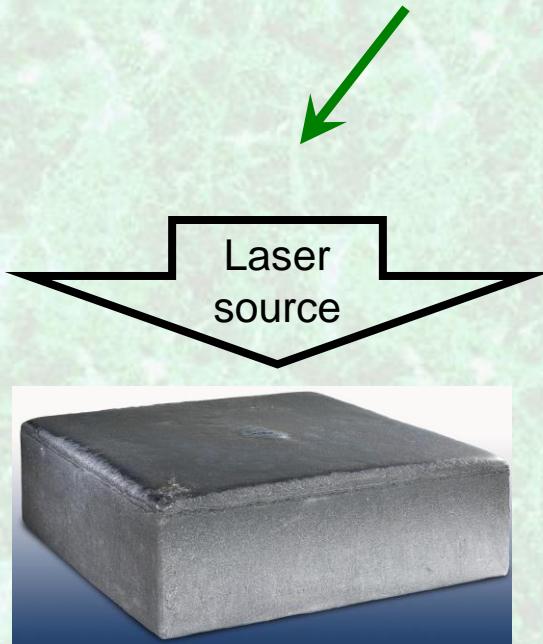


$$\frac{\partial T}{\partial t} = a \frac{\partial^2 T}{\partial x^2}$$

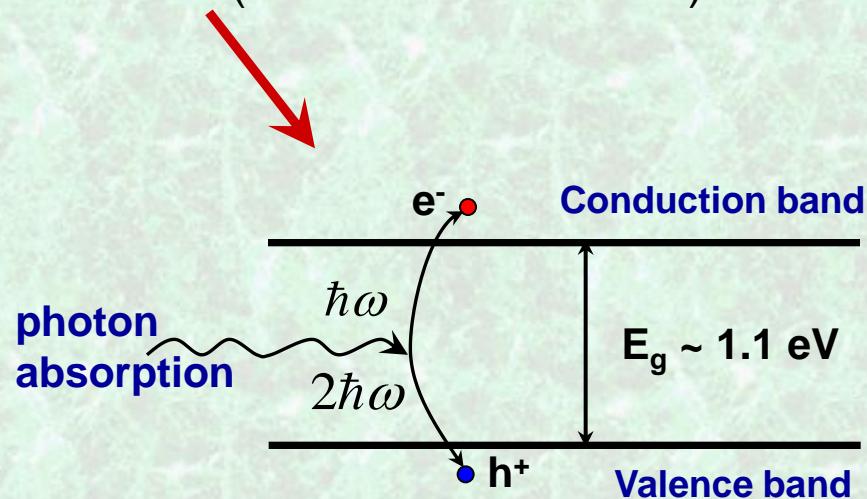
Continuum modeling for silicon

Based on: relaxation-time approximation of Boltzmann equation
(H.M. van Driel, Phys. Rev. B 35 8166 (1987))

Silicon : atoms and free carriers (electrons and holes)



(© Cyberstar)



$$f_{e,h}(E) = \frac{1}{e^{\frac{k_B T_{e,h}}{E - E_{F_{e,h}}}} + 1}$$

$$C_a \frac{\partial T_a}{\partial t} = \operatorname{div}(k_a \nabla T_a) + G(T_e - T_a)$$

Diffusion equation for atoms

Fermi-Dirac distributions
for electrons and holes

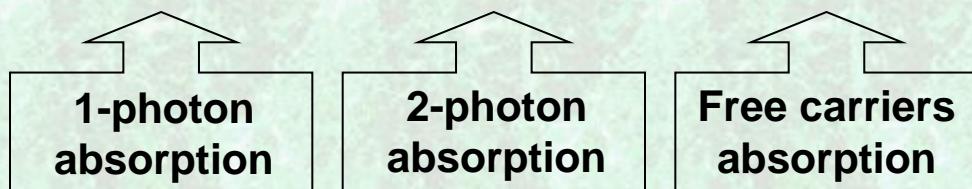
Continuum modeling for silicon

Energy conservations for carrier subsystem:

$$\frac{\partial U_e}{\partial t} = \text{Source}(\vec{r}, t) - \text{div} \vec{W}(\vec{r}, t) - G(T_e - T_L)$$



$$\text{Source}(\vec{r}, t) = \alpha I(\vec{r}, t) + \beta I^2(\vec{r}, t) + \Theta n I(\vec{r}, t)$$



Continuum modeling for silicon

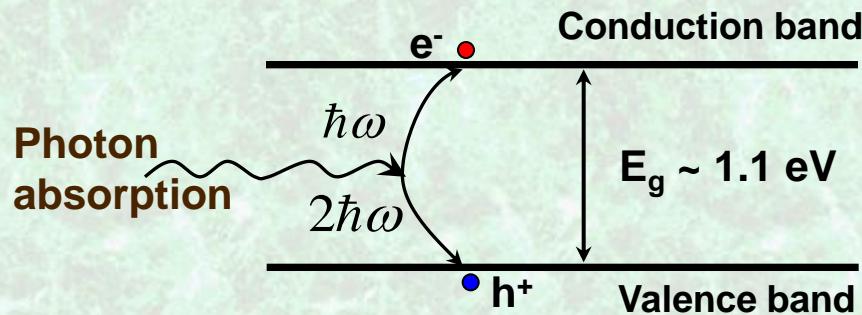
Carrier density and diffusion in conduction band

$$\frac{\partial n}{\partial t} =$$

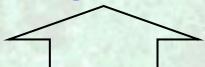


Density of carriers
in conduction band

Continuum modeling for silicon



$$\frac{\partial n}{\partial t} = Source_n(\vec{r}, t)$$

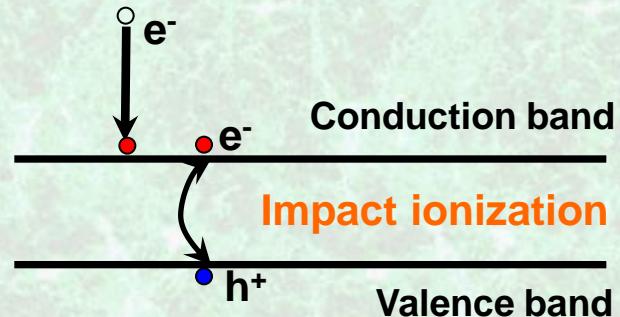
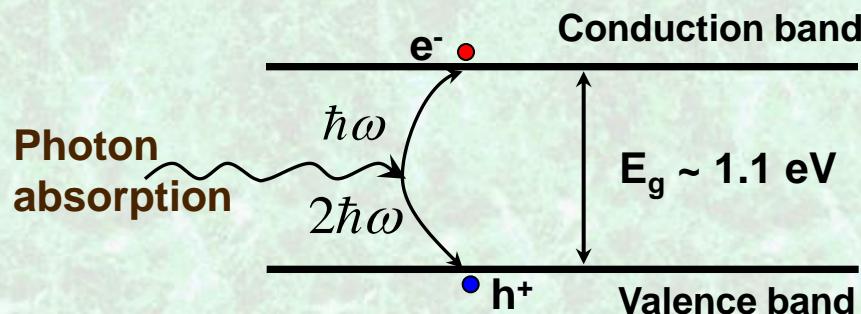


Density of carriers
in conduction band

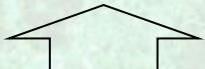


Excitation of
new carriers

Continuum modeling for silicon



$$\frac{\partial n}{\partial t} = Source_n(\vec{r}, t) + \theta n$$



Density of carriers
in conduction band

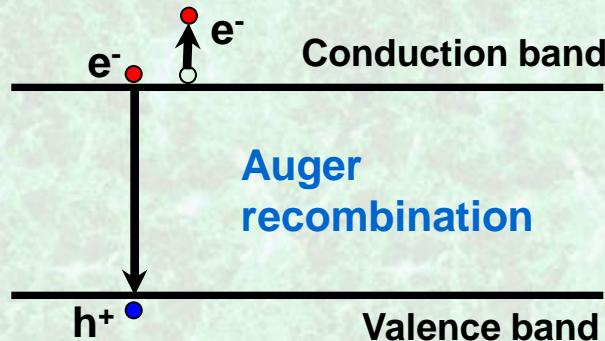
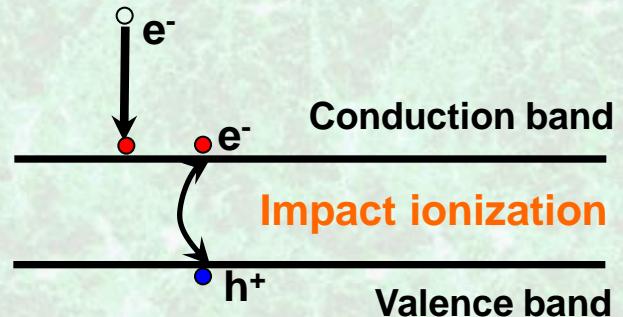
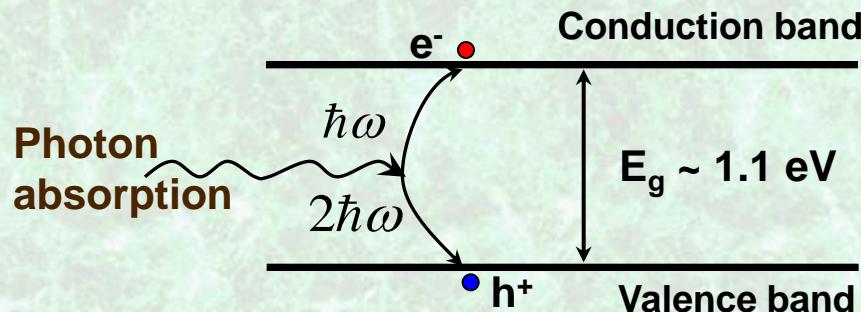


Excitation of
new carriers

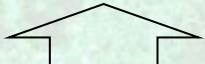


Impact
ionization

Continuum modeling for silicon



$$\frac{\partial n}{\partial t} = Source_n(\vec{r}, t) + \theta n - \gamma n^3$$



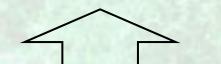
Density of carriers
in conduction band



Excitation of
new carriers

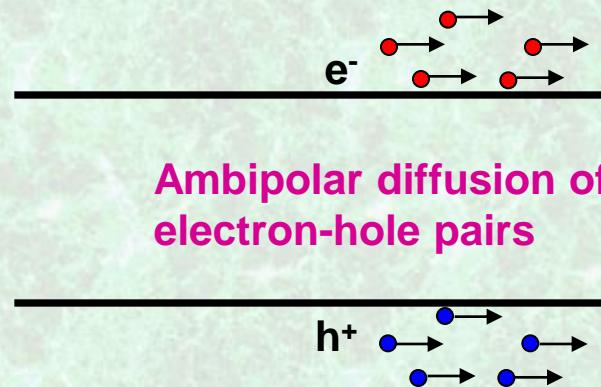
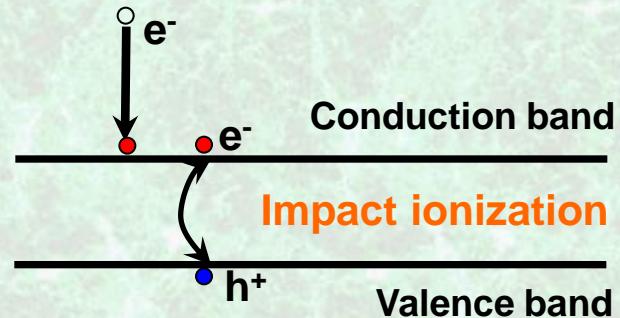
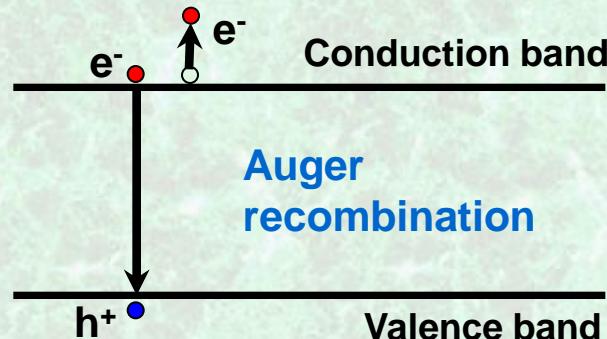
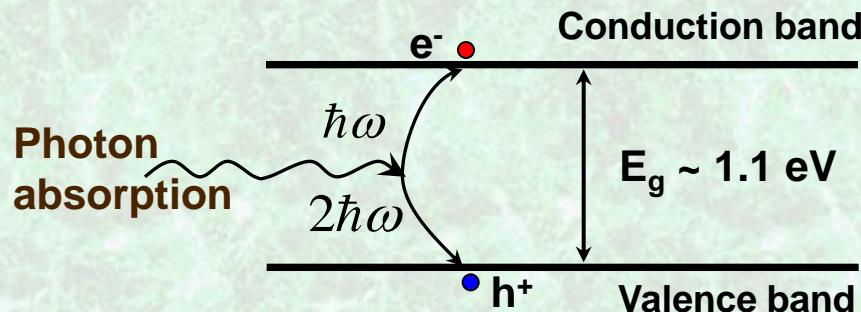


Impact
ionization

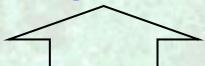


Auger
recombination

Continuum modeling for silicon



$$\frac{\partial n}{\partial t} = Source_n(\vec{r}, t) + \theta n - \gamma n^3 - \text{div}(\vec{J})$$



Density of carriers
in conduction band



Excitation of
new carriers



Impact
ionization



Auger
recombination



Ambipolar
diffusion

Continuum modeling for silicon

Self-consistent model on Si (analogue to TTM)

H.M. van Driel, Phys. Rev. B 35 8166 (1987)

$$\left\{ \begin{array}{l} \frac{\partial n}{\partial t} = \frac{\alpha I}{\hbar\omega} + \frac{\beta I^2}{2\hbar\omega} + \theta n - \gamma n^3 - \operatorname{div}(\vec{J}) \\ \\ \frac{\partial U}{\partial t} = (\alpha + \Theta n)I + \beta I^2 - \operatorname{div}(\vec{W}) - G(T_e - T_a) \\ \\ C_a \frac{\partial T_a}{\partial t} = \operatorname{div}(k_a \nabla T_a) + G(T_e - T_a) \end{array} \right.$$

Carrier density

Energy of excited carriers

Lattice temperature

Continuum modeling for silicon

Self-consistent model on Si (analogue to TTM)

H.M. van Driel, Phys. Rev. B 35 8166 (1987)

$$\left\{ \begin{array}{l} \frac{\partial n}{\partial t} = \frac{\alpha I}{\hbar\omega} + \frac{\beta I^2}{2\hbar\omega} + \theta n - \gamma n^3 - \operatorname{div}(\vec{J}) \\ \frac{\partial U}{\partial t} = (\alpha + \Theta n)I + \beta I^2 - \operatorname{div}(\vec{W}) - G(T_e - T_a) \\ C_a \frac{\partial T_a}{\partial t} = \operatorname{div}(k_a \nabla T_a) + G(T_e - T_a) \end{array} \right.$$

Carrier density

Energy of
excited carriers

Lattice
temperature

Laser source

Coupling term

Solution algorithm for continuum part

$$\left\{ \begin{array}{l} \frac{\partial U_e}{\partial t} = \underline{(\alpha + \Theta n)I + \beta I^2 - \operatorname{div}(\vec{W})} - \underline{G(T_e - T_a)} \\ U = nE_{gap} + \frac{3}{2}nk_B T_e \left[H_{\frac{1}{2}}^{\frac{3}{2}}(\eta_e) + H_{\frac{1}{2}}^{\frac{3}{2}}(\eta_h) \right] \end{array} \right.$$

Energy of
excited carriers

Connection between energy
and temperature for Fermi-particles

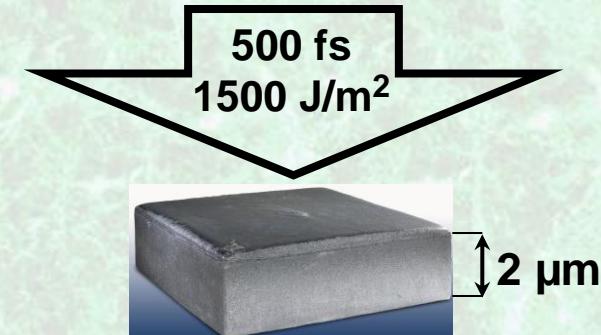
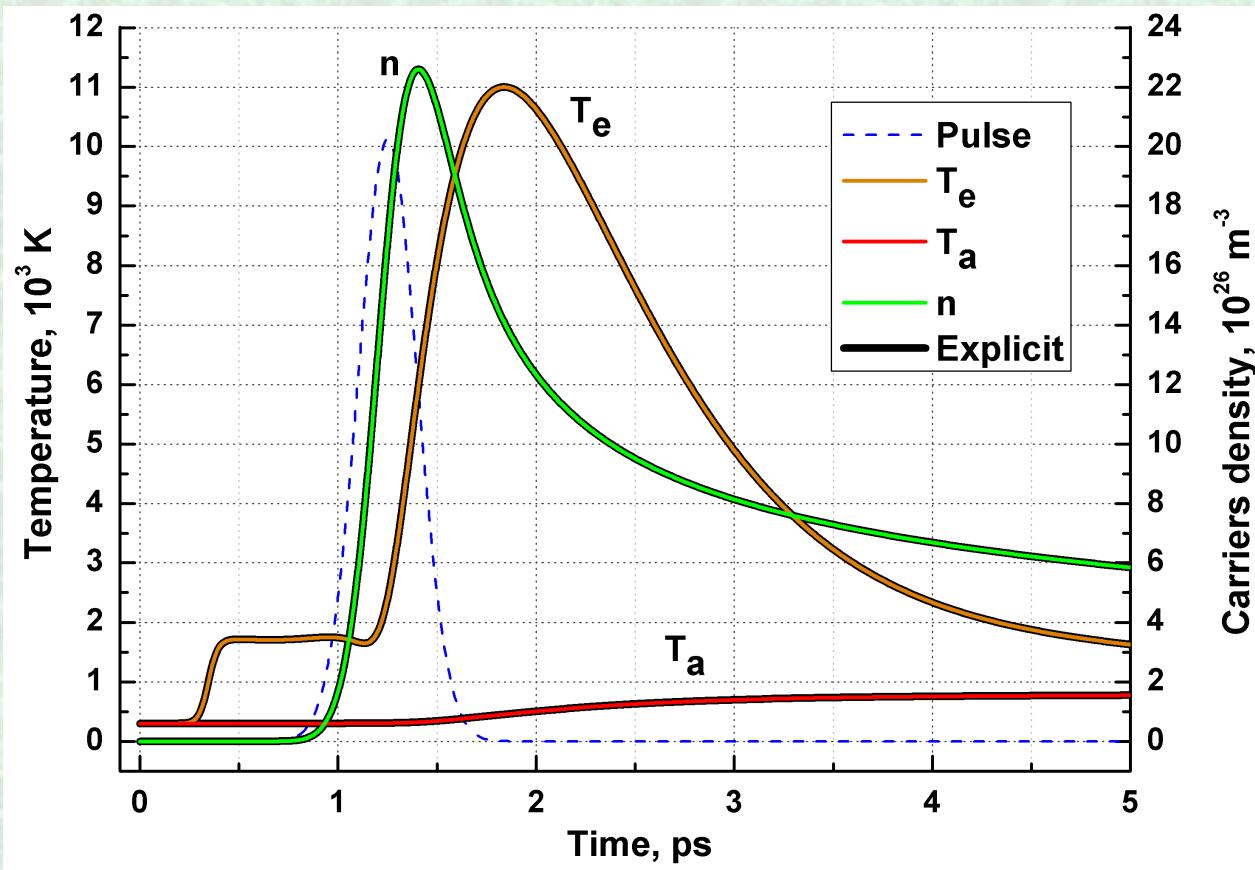
$$C_{e-h} \frac{\partial T_e}{\partial t} = \underline{(\alpha + \Theta n)I + \beta I^2 - \operatorname{div}(\vec{W}(T_e))} - \underline{\frac{C_{e-h}}{\tau}(T_e - T_l) + f(T_e, n)}$$

$$\frac{\partial T}{\partial t} = F\left(T, x, t, \frac{\partial T}{\partial x}, \frac{\partial^2 T}{\partial x^2}\right)$$

Diffusion equation. We use Crank-Nicolson half-implicit finite-differences method

Results of continuum calculations

Explicit and implicit schemes comparison



(© Cyberstar)

- First peak of T_e is due to small heat capacity of the carrier pairs
- Second peak of T_e is due to direct absorption by free carriers

Calculation time 17 hours decreased to 23 seconds

Models for laser interaction with matter

Two-temperature model (TTM):

- + accounts for electron-phonon nonequilibrium and fast electron heat conduction
- fails to describe kinetics of fast phase transition processes

$$\left\{ \begin{array}{l} \frac{\partial \mathbf{n}}{\partial t} = \frac{\alpha \mathbf{I}}{\hbar \omega} + \frac{\beta \mathbf{I}^2}{2\hbar \omega} + \Theta \mathbf{n} - \gamma \mathbf{n}^3 - \mathbf{div}(\bar{\mathbf{J}}) \\ \frac{\partial \mathbf{U}_e}{\partial t} = (\alpha + \Theta \mathbf{n}) \mathbf{I} + \beta \mathbf{I}^2 - \mathbf{div}(\vec{\mathbf{W}}) - \mathbf{G}(\mathbf{T}_e - \mathbf{T}_a) \\ \mathbf{C}_a \frac{\partial \mathbf{T}_a}{\partial t} = \mathbf{div}(\mathbf{k}_a \nabla \mathbf{T}_a) + \mathbf{G}(\mathbf{T}_e - \mathbf{T}_a) \end{array} \right.$$

Molecular dynamics (MD) method:

$$\mathbf{m}_i \frac{d^2 \vec{\mathbf{r}}_i}{dt^2} = \vec{\mathbf{F}}_i = - \sum_{j \neq i} \vec{\nabla}_{\vec{\mathbf{r}}_j} U(\vec{\mathbf{r}}_i - \vec{\mathbf{r}}_j); i = 1, \dots, N$$

- + can describe kinetics of fast nonequilibrium phase transition processes
- the classical MD method does not have free electrons included explicitly

Combine the advantages of different approaches
in a single model

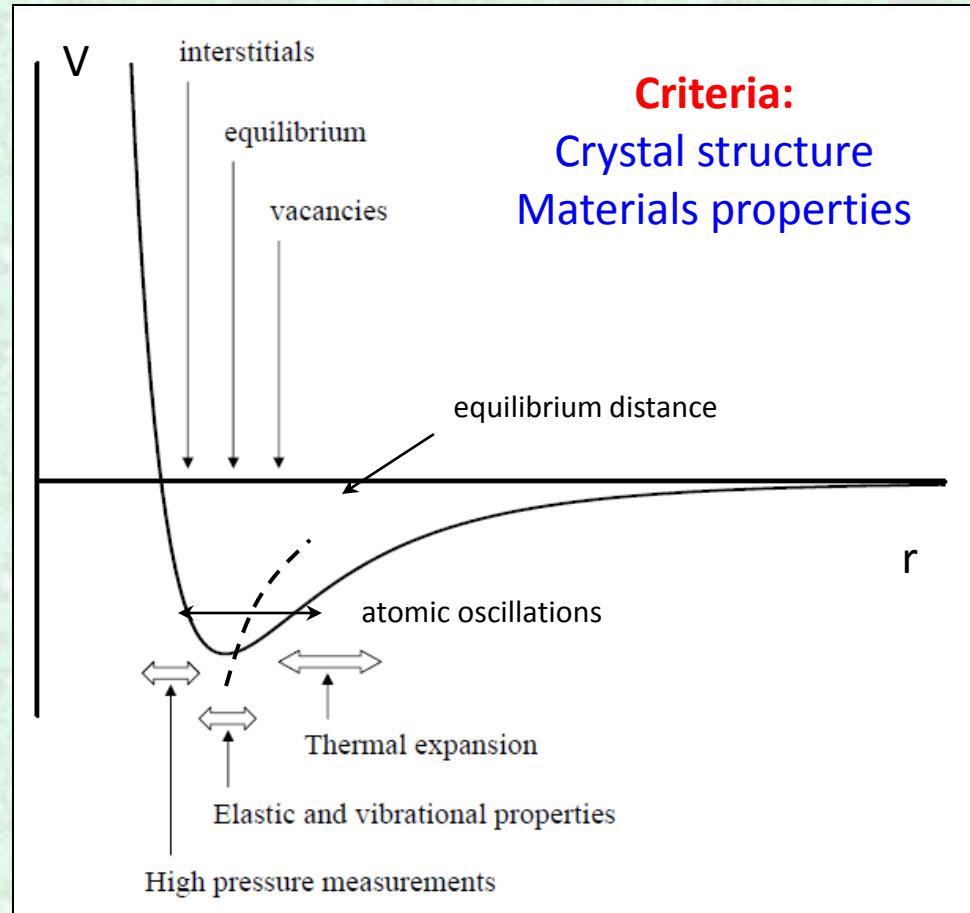
Choice of the potential of MD method

Molecular Dynamics:

$$m_i \vec{a}_i = \vec{F}_i = -\text{grad} V(\vec{r}_1, \vec{r}_2, \dots, \vec{r}_n)$$

Example: Lennard-Johns potential for Wan der Vaals interactions in inert gases Ar, Kr and molecular systems:

$$V = \sum_{i \neq j} U(r_{ij}) = \sum_{i \neq j} 4\epsilon \left(\left(\frac{r_{ij}}{\sigma} \right)^{12} - \left(\frac{r_{ij}}{\sigma} \right)^6 \right)$$

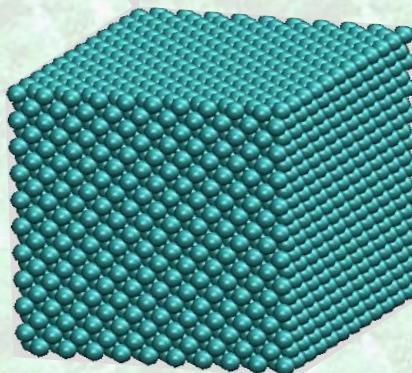
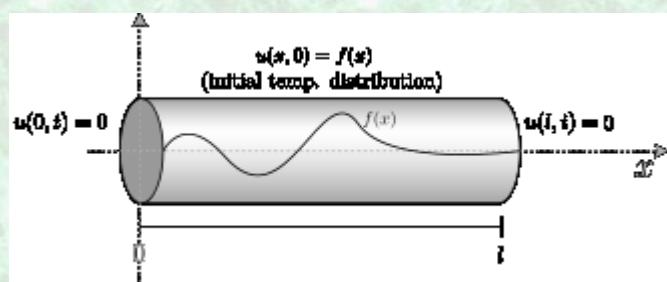


Stillinger-Webber potential with many body angular part for open diamond structures as in Si:

$$V = \frac{1}{2} \sum_{ij} U(r_{ij}) + \sum_{ijk} g(r_{ij})g(r_{jk}) \left[\cos \theta_{ijk} + \frac{1}{3} \right]^2$$

Part II

Atomistic-continuum modeling of silicon (MD-TTM)



The atomistic-continuum model for silicon

$$\frac{\partial n}{\partial t} = \frac{\alpha I}{\hbar\omega} + \frac{\beta I^2}{2\hbar\omega} + \theta n - \gamma n^3 - \operatorname{div}(\vec{J})$$

carrier density

$$\frac{\partial U_e}{\partial t} = (\alpha + \Theta n)I + \beta I^2 - \operatorname{div}(\vec{W}) - G(T_e - T_a)$$

electron-hole temperature

$$C_a \frac{\partial T_a}{\partial t} = \operatorname{div}(k_L \nabla T_L) + G(T_e - T_a)$$

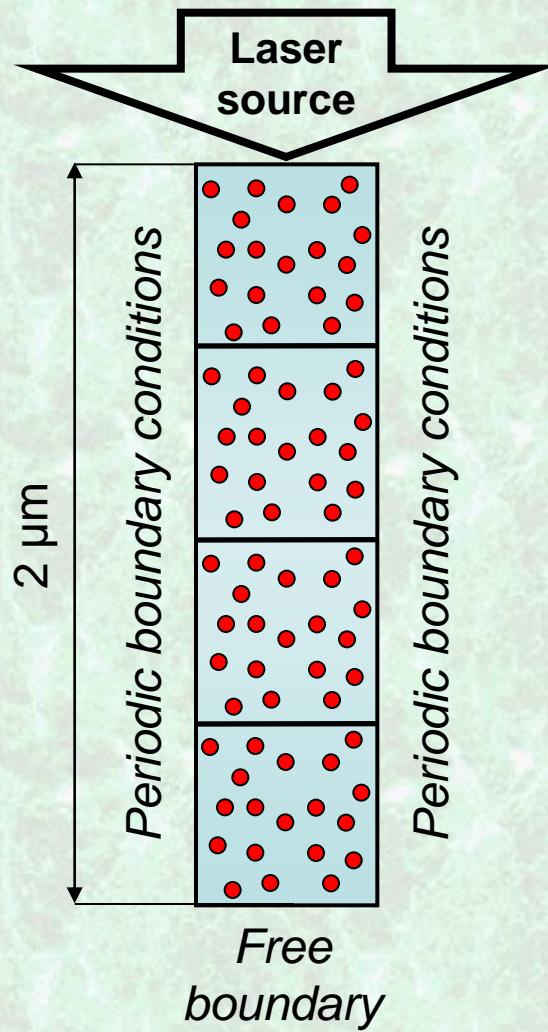
lattice temperature

Molecular dynamics for silicon atoms:
(Stillinger-Weber potential)

$$m_i \frac{d^2 \vec{r}_i}{dt^2} = \vec{F}_i + \xi m_i \frac{d\vec{r}_i^T}{dt}$$

The atomistic-continuum model for silicon

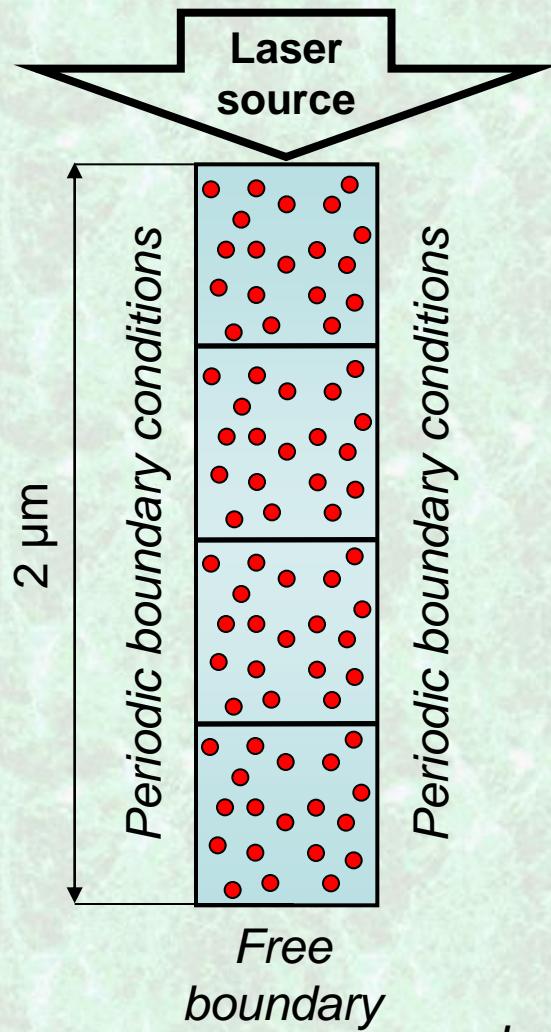
Coupling organization



$$G(T_e - T_a)$$

The atomistic-continuum model for silicon

Coupling organization



$$G(T_e - T_a)$$

Temperature of atoms:

$$\boxed{a \rightarrow e} \quad \langle E_{kin} \rangle = \sum_{i=1}^{N_{atoms}} \frac{m_i (v_i^T)^2}{2} = \frac{3}{2} kT$$

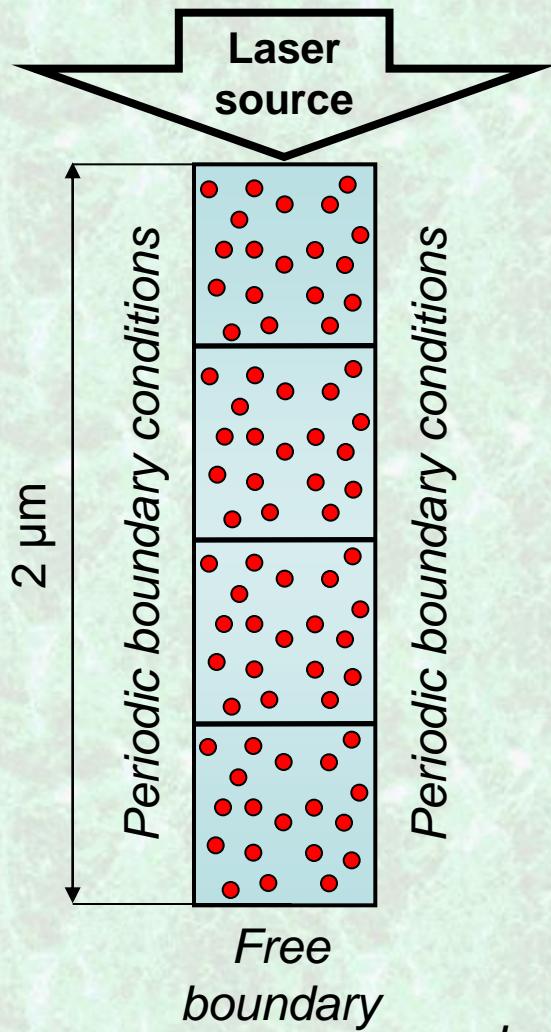
“Friction” term for Molecular Dynamics:

$$\boxed{e \rightarrow a}$$

$$m_i \frac{d^2 \vec{r}_i}{dt^2} = \vec{F}_i + \xi m_i \frac{d\vec{r}_i^T}{dt}$$

The atomistic-continuum model for silicon

Coupling organization



$$G(T_e - T_a)$$

Temperature of atoms:

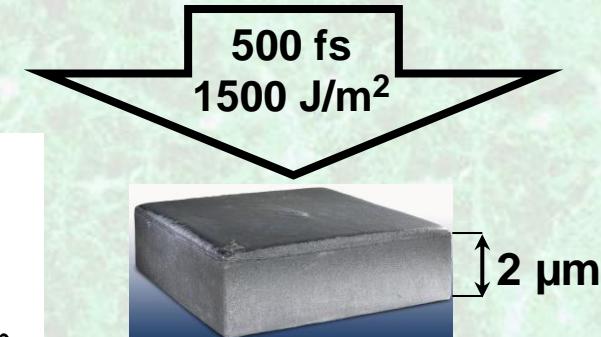
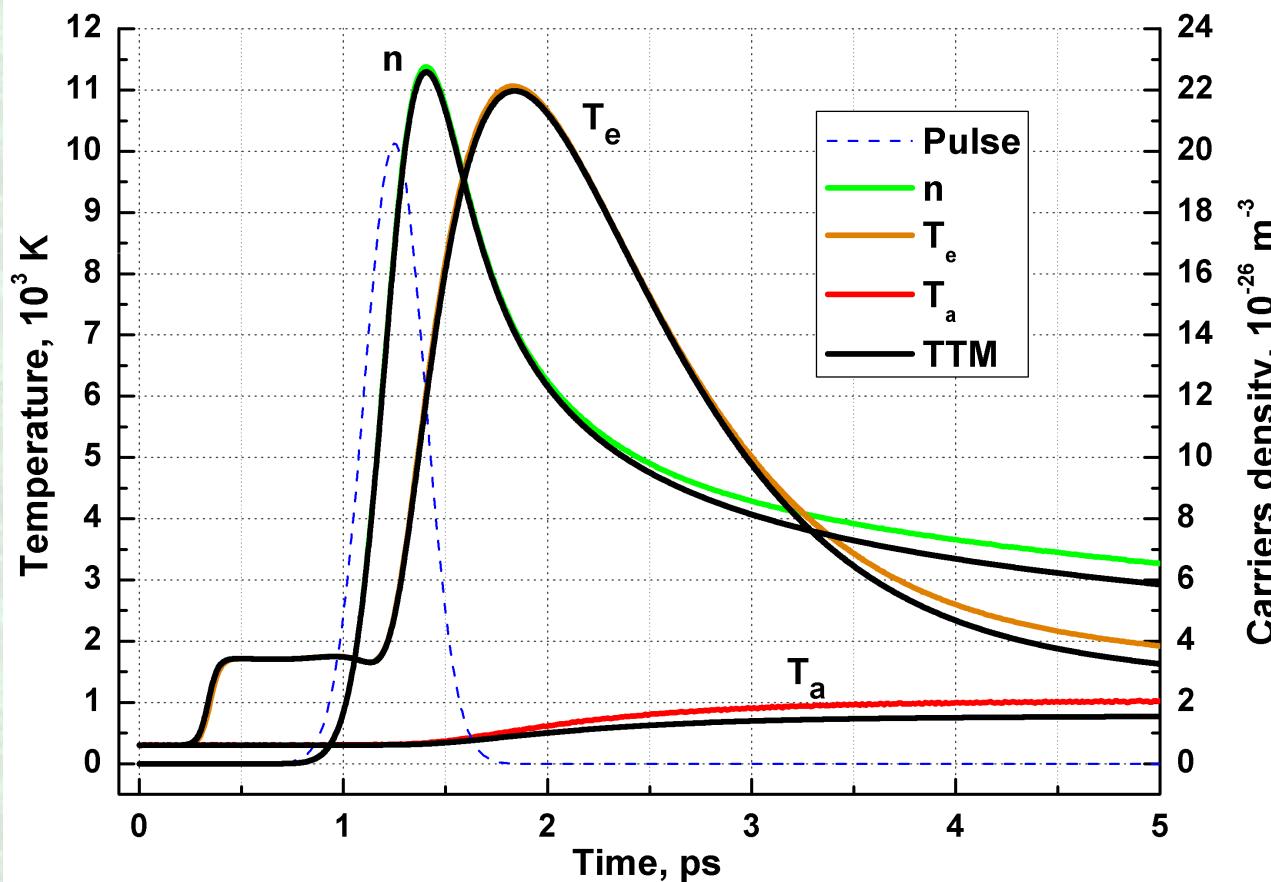
$$a \rightarrow e \quad \langle E_{kin} \rangle = \sum_{i=1}^{N_{atoms}} \frac{m_i (v_i^T)^2}{2} = \frac{3}{2} kT$$

“Friction” term for Molecular Dynamics:

$$e \rightarrow a \quad m_i \frac{d^2 \vec{r}_i}{dt^2} = \vec{F}_i + \frac{GV_N(T_e - T_a)}{2K^T} m_i \frac{d\vec{r}_i^T}{dt}$$

Results of MD-TTM calculations

MD-TTM compared to pure TTM

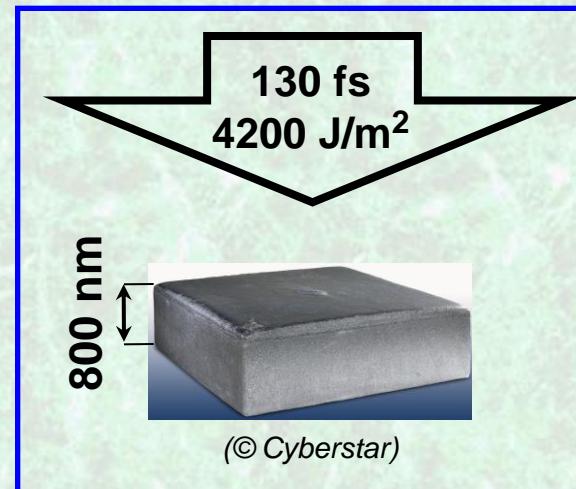
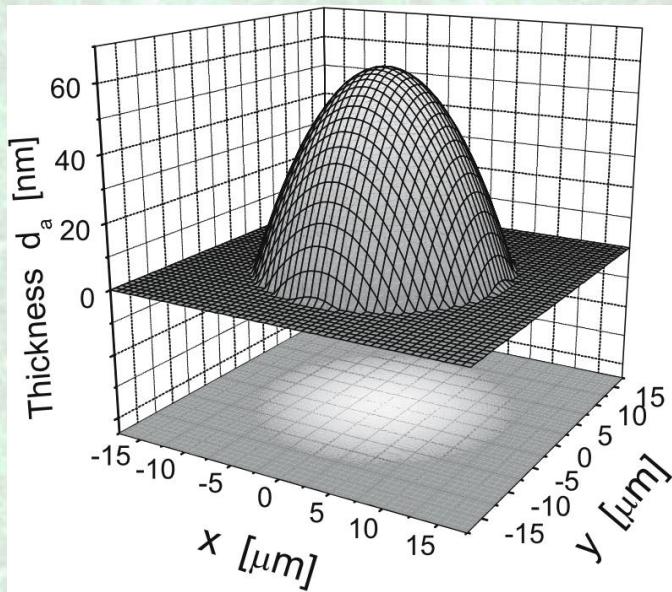


(© Cyberstar)

- Difference in T_a due to surface effects: expansion of the sample and surface energy
- No difference for undersurface cells

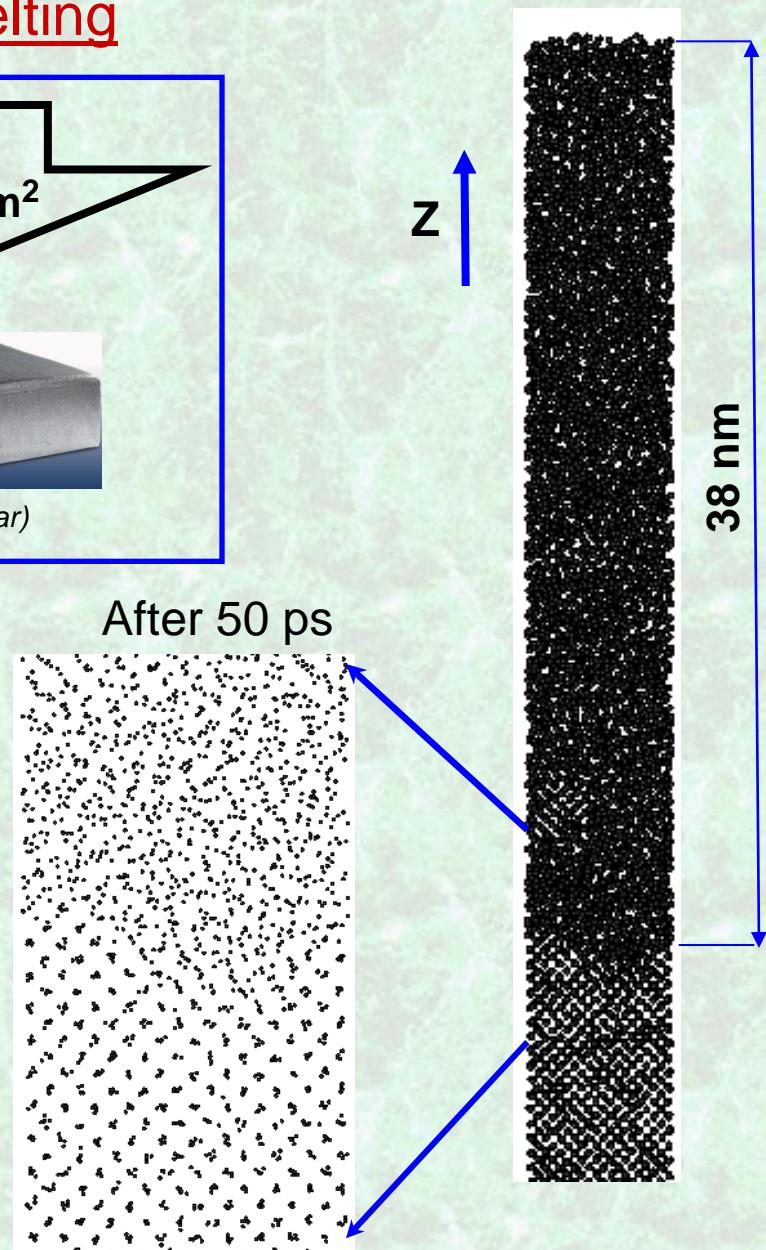
Results of MD-TTM calculations

Laser melting



Amorphous layer thickness induced by 130fs, 800nm laser pulse with fluence 4200 J/m²

J. Bonse, *Appl. Phys. A: Mater. Sci.*
Proc., A 84, 63-66 (2006)



Conclusion

- Time step of continuum model has been increased by 10^4 times
- The atomistic-continuum model for laser interaction with Si has been implemented
- First calculations show the correctness of the new model
- First calculation of laser melting shows good qualitative agreement with experiment

Future work

- Utilization of the modified potential* accounting for the changes in atomic bonding versus parameters of photoexcited carriers
- Implementation of electron diffusion in 3D
- Realization of parallel algorithm
- Direct comparison of the model with an experiment

*Shokeen, Schelling, J. Appl. Phys. 109, 073503 (2011)

Acknowledgements

DFG under “Geschaeftsziechen” IV 122/1-1 and IV 122/1-2

“Zeitaufgeloste Beobachtung und Modellierung der Entstehung laserinduzierter Nanostrukturen”



UNIKASSEL
VERSITÄT

Thank you for your attention!